Applicant(s): Tomohiko SHIBATA, Yukinori NAKAMURA, Mitsuhiro TANAKA and Keiichiro ASAI
Title: A METHOD FOR FAB
TING A III-V NITRIDE FILM AND AN AP
ATUS FOR FABRICATING
THE SAME

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FIG. 1A

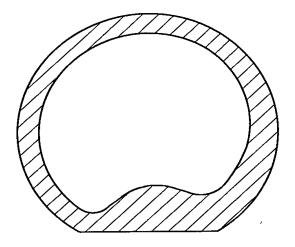
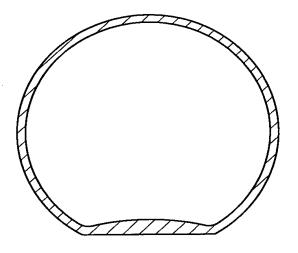


FIG. 1B

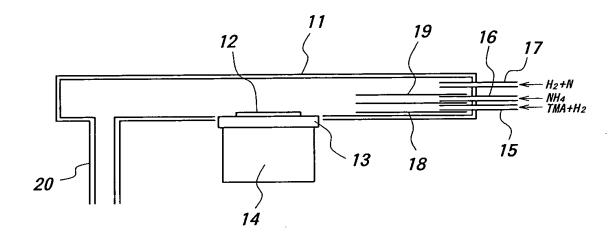
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FIG. 3

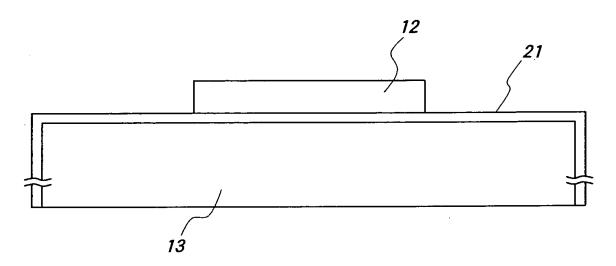


FIG. 4

